



DOCUMENT CHANGE REQUEST

DCR number	483	Changes required for:	Qualification	Originator:	nicolas martini
Date:	2009/03/30	Date sent:	2009/03/30	Organisation:	CNES
Status:	IMPLEMENTED				

Title: Resistors fixed film chips, based on type P HR

Number: 4001/023 Issue: 4

Other documents affected:

4001/025-4

Page:

1) Title :
2) Appendix A :
3) Appendix A :

Paragraph:

1) Title :
2) Appendix A :
3) Appendix A :

Original wording:

Proposed wording:

1) Title : Replace PHR with P or add PFR to PHR.
2) Appendix A : replace 2XXXX with 26000.
3) Appendix : In first box, Deviation from Generic specification, screening test (Chart F3):
add Para. 8.3.3 High and Low Temperature Measurement (TC)
TC measurements are performed at +25°C and +75°C at Front-end level on each wafer on 5 areas. -55°C/+155°C acceptance criteria are guaranteed through the correlation table given in VISHAY specification CM-SF-00210.

Justification:

1) Editorial change
2) Editorial change
3) Test reduction as agreed by VISHAY TRB and CNES.

Attachments:
N/A
Modifications:
<p>the following minor editorial amendments to the text to be included in the Detail spec on points 1 & 3 of DCR483 for clarification purposes:</p> <p>.....</p> <p>For 4001/023</p> <p>1 - amend title to be based on type "PHR and PFR" (similar to 4001/025)</p> <p>3 - Appendix A, add new item:</p> <p>Items Affected High and Low Temperatures Electrical Measurements</p> <p>Description of Deviations All tests at high and low temperatures are guaranteed but tested based on temperature coefficient measurements performed on each wafer at +25C and +75C in accordance with VISHAY specification CM-SF-00210.</p> <p>.....</p> <p>For 4001/025</p> <p>Only item 3 of DCR483 applies to 4001/025 (amended as follows):</p> <p>3 - Appendix A, add new item:</p> <p>Items Affected High and Low Temperatures Electrical Measurements</p> <p>Description of Deviations All tests at high and low temperatures are guaranteed but tested based on temperature coefficient and relative temperature coefficient measurements performed on each wafer at +25C and +75C in accordance with VISHAY specification CM-SF-00210.</p>
Approval signature:

Date signed:
2009-03-30